

INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.2758	Application No.	Not Yet Assigned
Applicant	Tetsuro NAKASUGI		
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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
<i>JP</i>	5,989,759	11/23/99	ANDO et al.	<i>—</i>	<i>—</i>	
<i>JP</i>	6,147,355	11/14/00	ANDO et al.	<i>—</i>	<i>—</i>	

FOREIGN PATENT DOCUMENTS

		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
JP		2960746	07/30/99	JAPAN			ABSTRACT
JP		2865164	12/18/98	JAPAN			ABSTRACT
JP		05-047649	02/26/93	JAPAN			ABSTRACT

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

JPB	ANDO, A. et al., "A Pattern Forming Method", U.S. Application Serial No.: 09/670,098, filed on September 26, 2000.
JPB	NAKASUGI, T. et al., "Charged Beam Exposure Method and Charged Beam Exposure Apparatus", U.S. Application Serial No. 09/465,932, filed on December 17, 1999.
JPB	NAKASUGI, T. et al., "Pattern Observation Apparatus and Pattern Observation Method", U.S. Application Serial No. 09/669,732, filed on September 26, 2000.

Examiner <i>Jack Berman</i>	Date Considered <i>2/18/04</i>
<p>*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	
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